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FEB 3 2000

Application Title: Laser Microcleaning Apparatus and Methods

Group 2700

Examiner/GAU / 2711

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: "Assistant Commissioner for Patents, Washington, D.C. 20231," on 1-28-00.

(Date of Deposit)

1-28-00

Theodore R. Touw

Date of Signature

Information Disclosure Statement

Commissioner of Patents and Trademarks

Washington, DC 20231

Sir:

Attached is a completed form PTO-1449 and copies of the pertinent parts of the references cited thereon. The examiner may find these references relevant to examination of this application. Inclusion of the references in this document is not an admission that any of the references are prior art to the subject invention. Applicant reserves the right to traverse characterization of any of the references herein as prior art. Following are comments on these references pursuant to 37 CFR §1.98; these comments are intended as a discussion of the relevance of these references to the patentability of each claim mentioned below:

The patents and publications submitted comprise the most pertinent art of which the applicant is aware, and it is believed that none of the references is relevant to the subject matter for which a patent is sought. None of the references shows the wafer-cleaning method of independent

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claim 1 and its dependent claims 2 - 19. None of the references shows the wafer-cleaning method of independent claim 20 and its dependent claims 21 - 23. None of the references shows the semiconductor wafer processing apparatus of independent claim 24 and its dependent claims 25 and 26. None of the references shows the wafer-cleaning method of independent claim 27 and its dependent claim 28. None of the references shows the wafer-cleaning method of independent claim 29 and its dependent claims 30 - 33. None of the references shows the semiconductor wafer processing apparatus of independent claim 34 and its dependent claims 35 and 36. None of the references individually or in combination fairly suggests applicant's invention as claimed.

Applicant would appreciate return of a copy of the form PTO-1449 submitted herewith, with each reference initialed by the Examiner to indicate that each initialed reference was considered by the Examiner.

Respectfully submitted,



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1-28-00

Date

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